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PATENT
09/864,714

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PreAmdt A
RABELL
9/30/02

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Ajit P. Paranjpe, et al.
Serial No.: 09/864,714
Filing Date: May 23, 2001
Title: ATOMIC LAYER DEPOSITION FOR
FABRICATING THIN FILMS

HONORABLE ASSISTANT COMMISSIONER
OF PATENTS
WASHINGTON, D.C. 20231

I hereby certify that this
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Heather Bergeron

06-13-01
Date

*Filed
Claims 1-26
12/18/02
@ 10:50am*

Dear Sir:

PRELIMINARY AMENDMENT

Prior to the initial review of the patent application
filed on May 23, 2001 by Ajit P. Paranjpe, et al., entitled
"Atomic Layer Deposition for Fabrication Thin Films", please
amend the application as follows:

IN THE SPECIFICATION

On Page 26, please replace the paragraph beginning on
Line 3 with the following:

--In one embodiment, the following parameters deposit a
desirable film: